APR 19 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hideaki Yamasaki, et al.

Confirmation No. 9914

Serial No.: 10/615,926

Group Art Unit: 1763

Filed: July 10, 2003

Examiner: J. R. Lund

Title: Film-Formation Apparatus and Source Supplying Apparatus Therefor,

Gas Concentration Measuring Method

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement dated April 12, 2005, Applicants hereby elect Claims 1-24 which, as stated in the Office Action, are drawn to a film formation apparatus.

If there are any questions regarding this response or the application in general, a telephone call to the undersigned would be appreciated since this should expedite the prosecution of the application for all concerned.

If necessary to effect a timely response, this paper should be considered as a petition for an Extension of Time sufficient to effect a timely response, and please charge any such fee or any deficiency in fees or credit any overpayment of fees to Deposit Account No. 05-1323 (Docket #010986.52578US).

April 19, 2005

Respectfully submitted,

Jeffrey D. Sano

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JDS:vgp